

FIG. 1

INTERFEROMETRY METHOD FOR ELLIPSOMETRY,
REFLECTOMETRY, AND SCATTEROMETRY MEASUREMENTS,
INCLUDING CHARACTERIZATION OF THIN FILM STRUCTURES

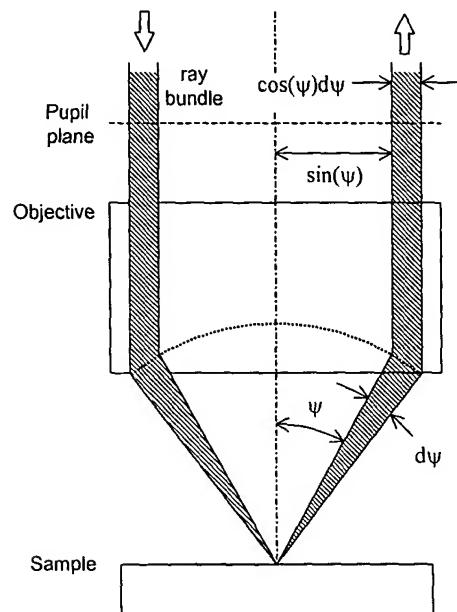


FIG. 2

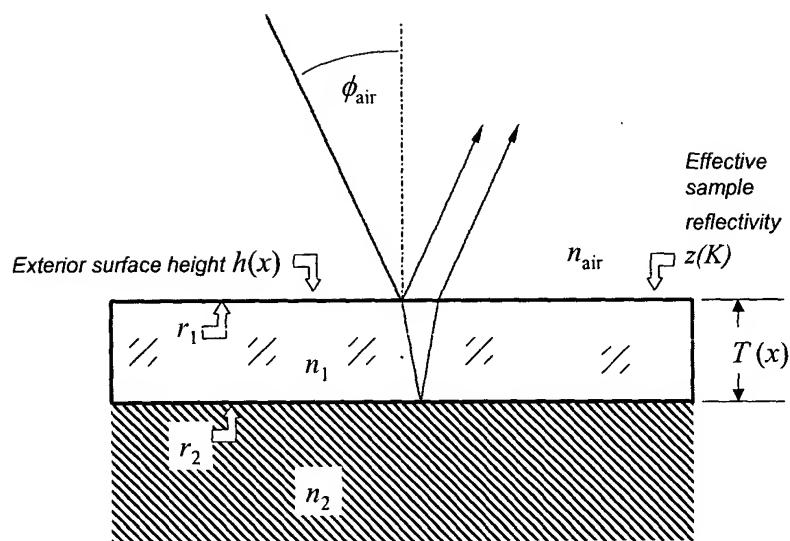


FIG. 3

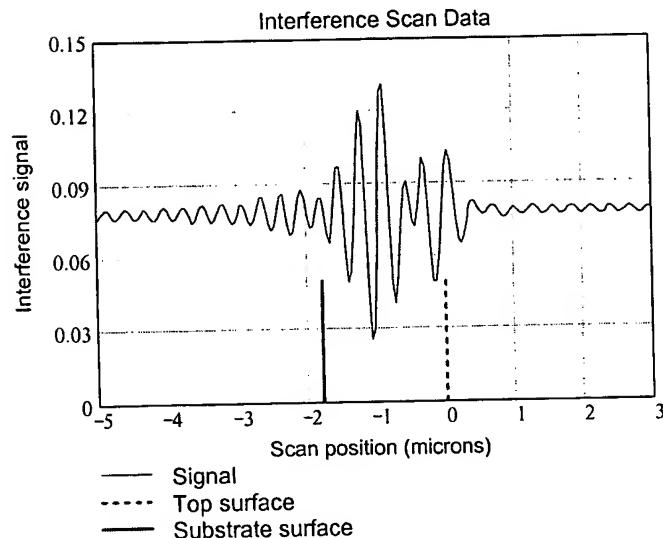


FIG. 4

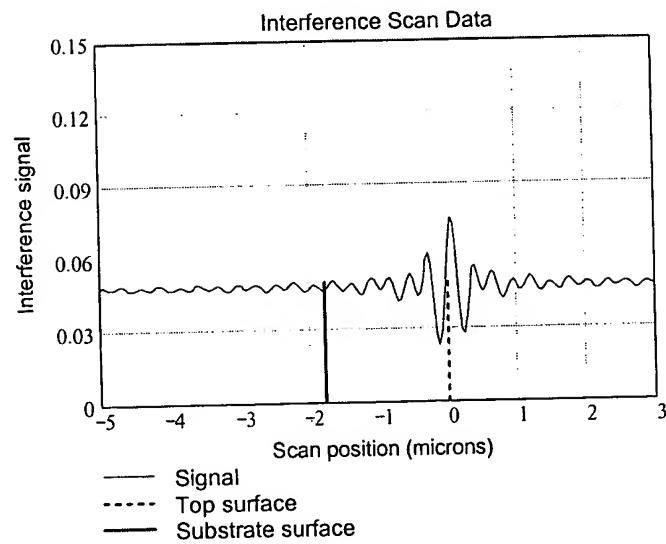
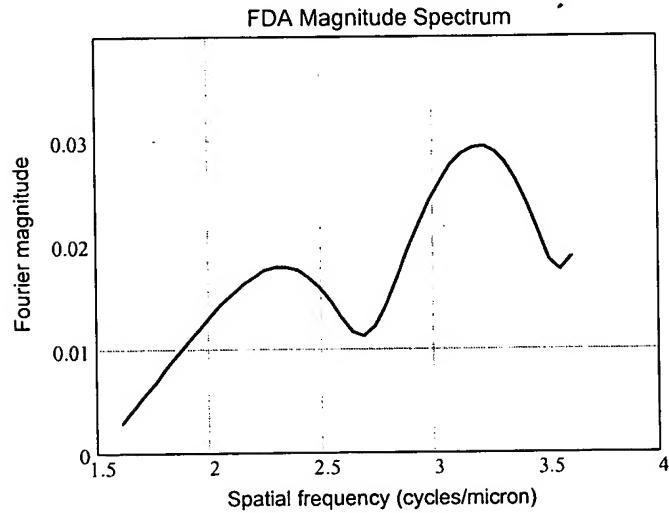
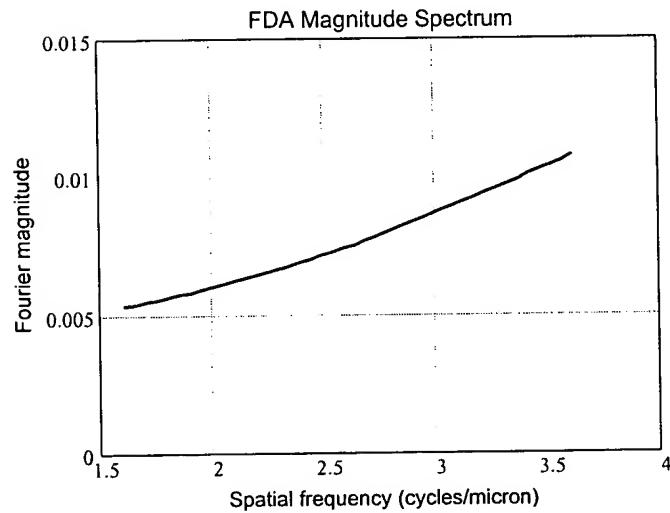


FIG. 5

**FIG. 6****FIG. 7**

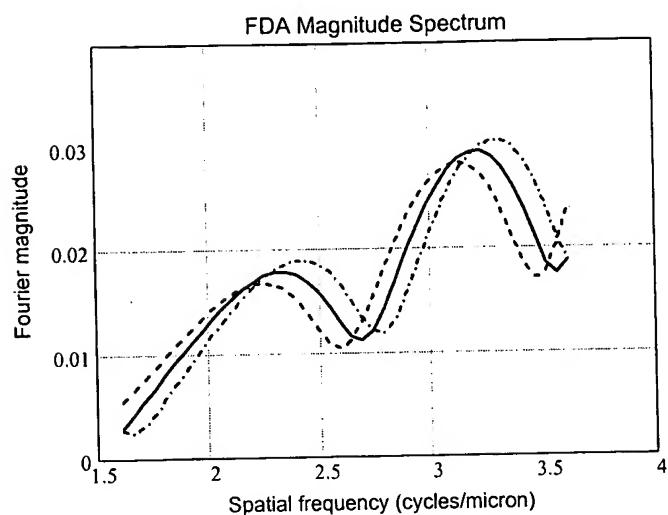


FIG. 8

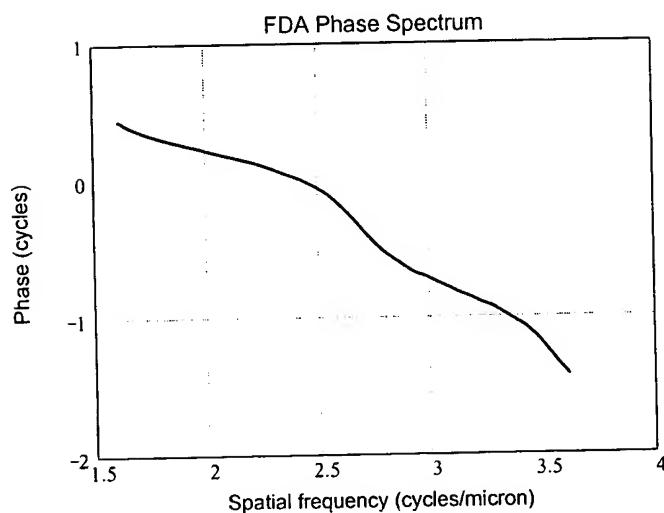


FIG. 9

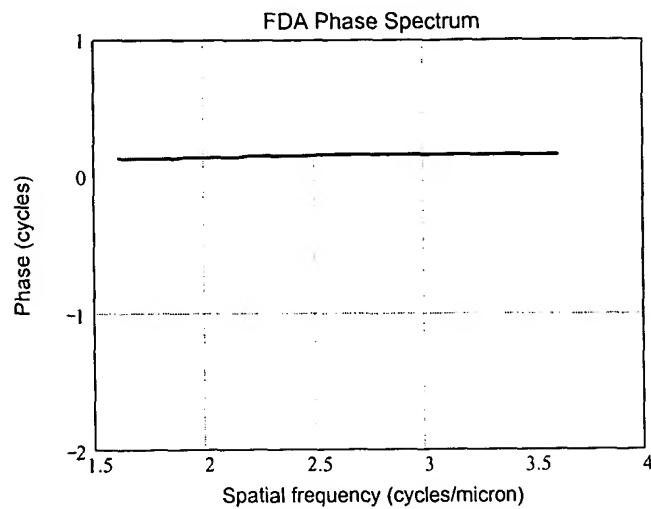


FIG. 10

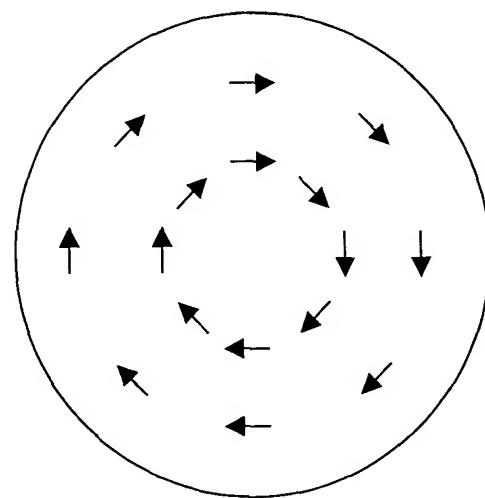
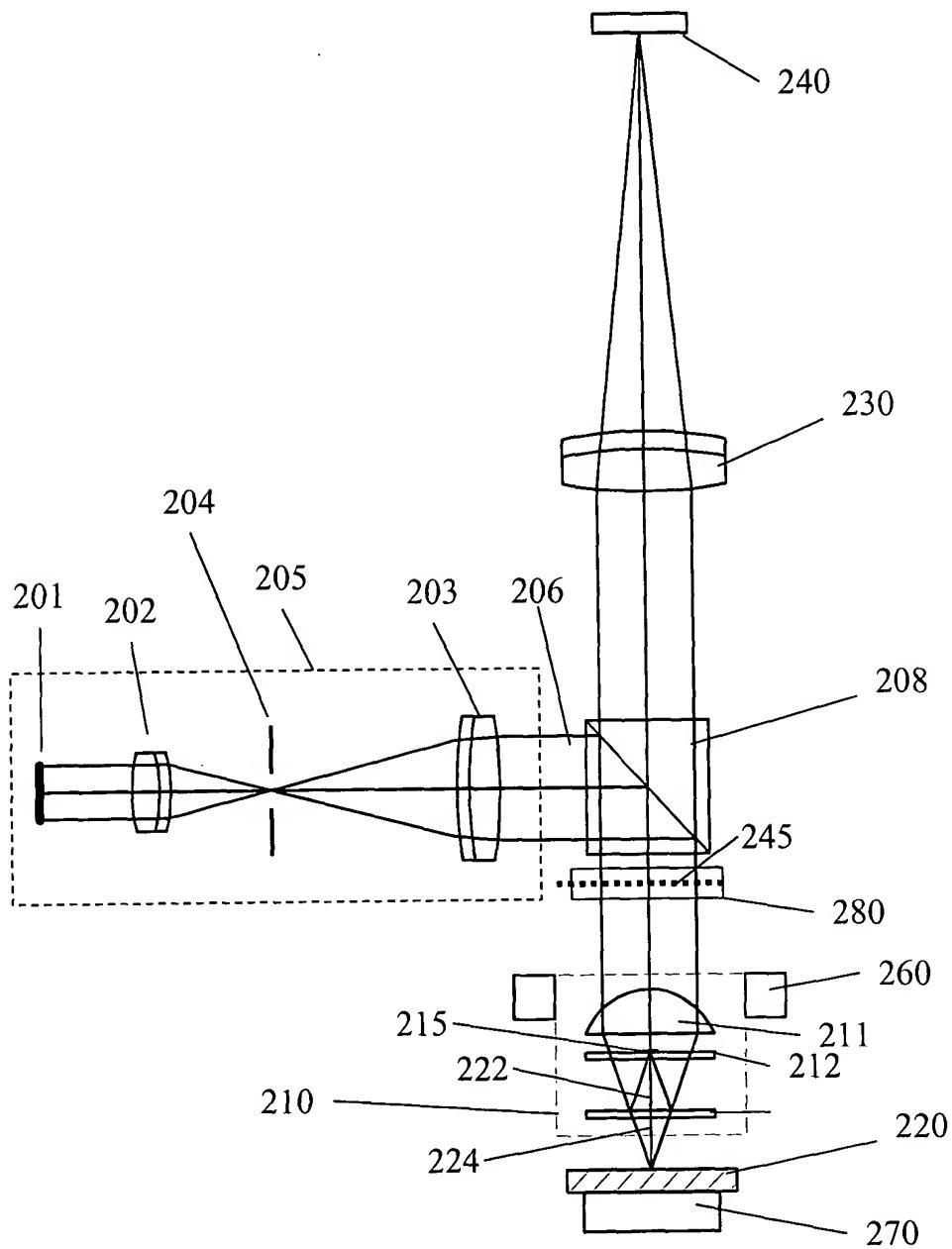


FIG. 12

**FIG. 11**